

<b>INFORMATION DISCLOSURE CITATION</b> PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO. P121-US		SERIAL NO. 10/713,671	
		APPLICANT Dmitri Simonian, et al.			
		FILING DATE 11/13/03		GROUP Not Yet Assigned	

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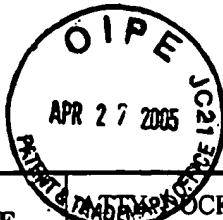
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
BT	2003/0002019	1/2/03	Miller			
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	2002/0063322	5/30/02	Robbins, et al.			
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
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BT	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICTION COATINGS FOR MEMS, Sensors and Actuators A 104 (2003), Pgs 213-221.
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



<b>INFORMATION DISCLOSURE CITATION</b>  <b>PTO-1449</b>  <b>SHEET 2 OF 2</b>		<b>INVENTOR SOCKET NO.</b> P121-US		<b>SERIAL NO.</b> Not Yet Assigned			
		<b>APPLICANT</b> Dima Simonian, et al.					
		<b>FILING DATE</b> Herewith		<b>GROUP</b> Not Yet Assigned			
<b>U.S. PATENT DOCUMENTS</b>							
<b>EXAMINER'S INITIALS</b>	<b>PATENT NO.</b>	<b>DATE</b>	<b>NAME</b>	<b>CLASS</b>	<b>SUBCLASS</b>	<b>FILING DATE</b>	
BT	2004/0012838	1/22/04	Huibers				
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<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
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<b>U.S. PATENT DOCUMENTS</b>							
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BT	Uthara Srinivasan, et al., ALKYLTRICHLOROSILANE-BASED SELF-ASSEMBLED MONOLAYER FILMS FOR STRICTION REDUCTION IN SILICON MICROMACHINES., Journal of Microelectromechanical Systems, Vol. 7, No. 2 June 1998, Pgs 252-260.						
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